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U.S. UTILITY Patent Application

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APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
0072931	02/12/2002	438		2812	

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****CONTINUING DATA VERIFIED:**

****FOREIGN APPLICATIONS VERIFIED:**
JAPAN 2001-040837 02/16/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☒ yes ☐ no
35- USC 119 conditions met ☒ yes ☐ no

ATTORNEY DOCKET NO

Verified and Acknowledged Examiner's initials

SDF

740756-2433

TITLE : Method of manufacturing a semiconductor device

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